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PTO/SB/08b (08-03) (AW 10/2003)

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Substitute for Form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)	Complete if Known	
	Application Number	To Be Assigned
	Filing Date	Herewith
	First Named Inventor	Ming Li et al.
	Art Unit	To Be Assigned
	Examiner Name	To Be Assigned
SHEET 1 of 1		Attorney Docket No. MATG-401US

NON-PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (In CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
AE	1.	MING LI ET AL., Nanostructuring in submicron-level waveguides with femtosecond laser pulses, Optics Communications, Elsevier Science B.V., September 2002, (5 pgs.)	<input type="checkbox"/>
AE	2.	MING LI ET AL., Ultra-precision machining using fs fast Laser: An application for Photonic Crystal fabrication, Fs Ultra-machining Workshop, March 5, 2003, (53 pgs.)	<input type="checkbox"/>
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Examiner Signature	M. Alexandra Elve		Date Considered 3/4/06

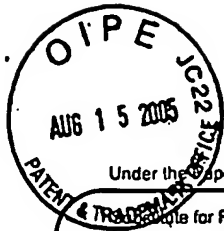
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¹Applicant's unique citation designation number (optional).

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

SHEET 1 of 1

Complete if Known

Application Number	10/790,401
Filing Date	March 1, 2004
First Named Inventor	Ming Li et al.
Art Unit	2812
Examiner Name	Steven J. Fulk
Attorney Docket No.	MATG-401US

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
AC	1.	LI M. et al.: "Femtosecond Laser Micromachining of Si-on-SiO ₂ for Photonic Band Gap Crystal Fabrication"; Japanese Journal of Applied Physics; Publication Office Japanese Journal of applied Physics; Tokyo, JP, vol. 40, no. 5A, Part 1, May 2001 (2001-05), pages 3476-3477; XP001078634; ISSN: 0021-4922	<input type="checkbox"/>
	2.	KORTE F. et al.: "Toward Nanostructuring with Femtosecond Laser Pulses"; Nanotechnology, 19-21 May 2003, Maspalomas, Gran Canaria, Spain, Proceedings of the SPIE, vol. 5118, 2003, pages 93-100, XP002326971; USA, ISSN: 0277-786X	<input type="checkbox"/>
	3.	WATANABE, OSAMU et al.: "Nanofabrication induced by near-field exposure from a nanosecond laser pulse"; Applied Physics Letters, American Institute of Physics, New York, US, vol. 79, no. 9, August 27, 2001 (2001-08-27), pages 1366-1368, XP012030175; ISSN: 0003-6951	<input type="checkbox"/>
	4.	ENDERS, O. et al.: "Lorentz-Force-Induced Excitation of Cantilevers for Oscillation-Mode Scanning Probe Microscopy"; German-Chinese Workshop on Fundamentals and Applications of Nanoscience: Building Blocks, Modelling and Structuring, 1-4, July 2002, Karlsruhe, Germany, Surface and Interface Analysis Wiley, vol. 36, no. 2, February 2004 (2004-02), pages 119-123, XP009047231; UK, ISSN: 0142-2421, section "Microstructuring the Cantilever Chip", page 120	<input type="checkbox"/>
AC	5.	OSTLENDER A. et al.: "Metrology for Laser-Structured Microdevices by CCD-Camera-Based Vision Systems"; Moems and Miniaturized Systems, 18-20, Sept. 2000, Santa Clara, CA, USA, Proceedings of the SPIE, vol. 4178, 2000, pages 197-206, XP002326972, USA, ISSN: 0277-786X, page 199, "3. Metrology for 3D Measurements", page 203, "7. Tests"	<input type="checkbox"/>
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Examiner Signature	M. Alexandra Elie	Date Considered	3/4/06
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